

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**  
**EXPEDITED PROCEDURE PURSUANT**  
**TO 37 CFR §1.116 REQUESTED**  
**Attn: Mail Stop AF**

In re the Application of:

Ji Yong PARK et al.

Application No. 10/690,507

Group Art Unit: 1792

Confirmation No. 6043

Filed: October 23, 2003

Examiner: Matthew J. Song

For: METHOD FOR MANUFACTURING POLYCRYSTALLINE SILICON THIN FILM AND  
THIN FILM TRANSISTOR FABRICATED USING POLYCRYSTALLINE SILICON THIN  
FILM MANUFACTURED BY THE MANUFACTURING METHOD

**RESPONSE AFTER FINAL REJECTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**February 26, 2008**

Attention: **BOX AF**

Sir:

This is in response to the in-person Office Interview scheduled and conducted at 1pm on Tuesday February 26, 2008 and the outstanding Office Action mailed November 26, 2007, and having a period for response set to expire on February 26, 2008.

Reconsideration of the claims is respectfully requested. The following remarks are respectfully submitted.